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								Filing Date: 12/20/01			
							Inventors: Vlad J. Novotny Yee-Chung Fu				
''Multi-Axis Micro-Electro-Mechanical Actuator'' Group Art Unit:											
						Exami	ner Name:	Unknown			
Attorney Docket AO-001								No.:			
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Sheet 1 of 1 Department of Commerce, Patent and Trademark Office Serial No.: 10/032,198 Filing Date: 12/20/01 SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY Inventors: Vlad J. Novotny APPLICANT Yee-Chung Fu "Multi-Axis Micro-Electro-Mechanical Actuator" Group Art Unit: 2874 2873 Examiner Name: Unknown Attorney Docket No.: AO-001 U.S. Patent Documents *Examiner Document Initial Filing Date, Date Number Name Class Subclass Τf Appropriate AA 5,724,123 ۰ کارنی 03/03/98 Tanaka 356 5.01 w.c AB 6,320,993B1 11/20/01 Laor 385 16 Foreign Patent Documents Translation Document Date Country Class Number Subclass Yes No AC OTHER ART (Including Author, Title, Date, Pertinent Pages, Efc.) "Silicon micromachines for lightwave networks: the little machthes that "Silicon micromachines for lightwave networks. the will make it big," by David Bishop. December 2000. SPIE'S Openion AD ٠٠. ١ ΑE AF AG AΗ

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